



***IN THE UNITED STATES PATENT AND TRADEMARK OFFICE***

Applicants: Shinichiro KOTAKE, et al.  
Title: FLUE GAS TREATING SYSTEM AND PROCESS  
Appl. No.: 09/658,928  
Filing Date: September 11, 2000  
Examiner: Wayne A. Langel  
Art Unit: 1754

**AMENDMENT AND RESPONSE UNDER 37 C.F.R. §1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

This is a response to the Office Action mailed on March 9, 2004, in connection with the captioned application.

**Amendments to the Claims** are reflected in the listing of claims beginning on page 2 of this document.

**Remarks** begin on page 6 of this document.

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02 FC:1203

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